

In the Claims:

Claims 19 and 20, amend to read as follows:

19. (Thrice Amended) An apparatus for depositing a material having a work function of approximately 1eV on a substrate by laser ablation using short-wavelength photons, including:

a deposition chamber,

a target containing a material having a work function of approximately 1eV in said chamber,

*D1*  
*SW*  
*4U*

a laser capable of directing photons at or below visible wavelength into said chamber and onto said target,

means for rotating said target,

means for controlling the composition of the deposit by controlling at least one of the groups consisting of the environment of said deposition chamber, the target composition, and the target temperature.

a substrate located in said chamber,

means for holding said substrate,

means for rotating and tilting said substrate, and

means for processing the surface of the substrate.

20. (Amended) The apparatus of Claim 19, additionally including means for heating and cooling said substrate.